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IN THE SPECIFICATION

Change the title at the top of page 1 and page 18 to:

"Method for Making A Vacuum Microelectronic Device"

IN THE ABSTRACT

Replace the Abstract on page 18 with the following:

A method of forming a vacuum microelectronic device includes steps of forming at least one electron emitter on a substrate, applying a first electric field to move a portion of the at least one electron emitter in a direction toward the first electric field, and maintaining the at least one electron emitter in the direction after removing the first electric field.

IN THE CLAIMS

Please cancel claims 7-20 without prejudice.